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(54) Title: HEIGHT SENSING SYSTEM FOR ELECTRON BEAM METROLOGY TOOL

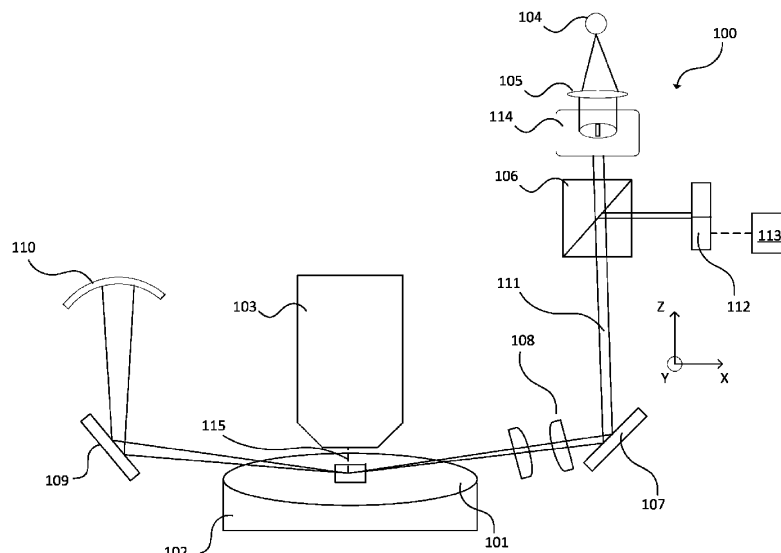


FIG. 1

(57) Abstract: A beam of light is directed at a workpiece on a stage. The workpiece is disposed an absolute distance from an electron beam column. The beam of light that is reflected off the workpiece is received at a sensor. Using the beam of light, a nominal distance between the electron beam column and the workpiece on the stage is determined.

[Continued on next page]

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